

## ABSTRACT OF THE DISCLOSURE

A reticle stage moves while holding the reticle.  
A stage controller detects the acceleration of the  
5 reticle stage based on the results of detection of an  
laser interference system. A main control system  
controls movement of the reticle stage so that the  
acceleration detected by the reticle stage becomes  
within a predetermined range of acceleration of the  
10 reticle stage where offset will not occur in the  
reticle. An image of the pattern formed on the reticle  
is transferred to a wafer through a projection optical  
system while synchronously moving the reticle and the  
wafer.